

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:	)	
Mitsuhiro ICHIJO et al.	)	Confirmation No. 7738
Application No. 10/804,053	)	Examiner: Long Pham
Filed: March 19, 2004	)	Group Art Unit: 2814
For: FILM FORMATION METHOD AND	)	
MANUFACTURING METHOD OF	)	Date: October 26, 2007
SEMICONDUCTOR DEVICE	)	

**AMENDMENT AFTER FINAL**

**MAIL STOP RCE**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the final Office Action mailed August 3, 2007, Applicants respectfully request reconsideration and allowance of the above-identified application in view of the following amendments and remarks.

**Amendments to the Claims** begin on page 2 of this paper.

**Remarks** begin on page 14 of this paper.